



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Grimbergen et al.	Group Art Unit: 1763
Application No: 09/595,778	Examiner: Allan W. Olsen
Confirmation No: 6490	Attorney Docket No: 2077 USA D01/ETCH/SILICON/MDD
Filed: June 16, 2000	
Title: APPARATUS AND METHOD FOR MONITORING PROCESSING OF A SUBSTRATE	April 21, 2009 San Francisco, California

**RESPONSE TO OFFICE ACTION**

VIA US MAIL

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450


Examiner Olsen:

This communication is in response to the first Office Action dated January 21<sup>st</sup>, 2009, and is being timely filed within three months thereof.

**CERTIFICATE OF TRANSMISSION**

I hereby certify that this correspondence is being deposited with the U.S. Postal Service with sufficient postage as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, facsimile transmitted to the U.S. Patent Office at (571) 273-8300, or filed electronically via EFS on the date shown below.

By: \_\_\_\_\_

  
Amy Wells

Date: April 21, 2009